IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Vikram Singh et al.

SERIAL NO.: 10/805,966 EXAMINER: Alejandron Mulero, Luz L.

FILED: March 22, 2004 ART UNIT: 1792

FOR: Plasma Immersion Ion Implantation Apparatus and Method

Mail Stop Amendment Commissioner For Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

In response to the Final Office Action dated March 18, 2008, Applicants file concurrently herewith a Request for Continued Examination and a Petition for Extension of Time under 37 CFR 1.136(a) in the above identified application. Although Applicants do not believe additional fees are necessary, Applicants request the Patent Office to charge any necessary fee or credit overpayment to the deposit account No. 50-0896.

Claims can be found on pages 2-8.

Remark can be found on pages 9-20.

1